Test Fabrication of a Copper Beam Duct for the KEK B-Factory

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Abstract

A trial model of copper beam duct for the KEK B-Factory was fabricated and gas desorption rates were measured. The duct consists of a cooling channel, a beam channel and a pump channel, which were extruded separately and welded each other by the electron beam welding. The duct received only ultrasonic cleaning in a freon bath. The ultimate total pressure was about $4 \times 10^{-10}$ Torr after a baking at 150°C for 48 hours and the thermal gas desorption rate was calculated as about $1.5 \times 10^{-12}$ Torr l/(s. cm$^2$) in N$_2$ equivalent. The measurement of the photon stimulated gas desorption rate was performed using the synchrotron radiation with a critical energy of 26.3 keV from the TRISTAN Accumulation Ring. The photo-desorption coefficients in the order of $10^{-2}$ molecules/photon were observed for main gases desorbed at the initial stage. These high gas desorption rates indicate that more careful surface preparation must be necessary.

I. INTRODUCTION

For the purpose of achieving a high luminosity, KEK B-Factory rings are operated with high current beams. Intensity of synchrotron radiation (SR) emitted from beams consequently becomes higher than any other existing $e^−$ e$^+$ collider. How to treat this intense SR is a major subject in designing the vacuum system [1].

The choice of duct material, among others, has been the most important R&D point confronting us. Prospective materials are copper and aluminum alloy. Copper has many excellent properties, i.e. a high thermal conductivity, a high melting point and a low photo-desorption coefficient. Our little experience on fabricating copper ducts on a large scale, however, was one problem compared to aluminum case.

We have made a trial model of copper duct to see the capability of the existing fabrication technique and to get a base for the final duct design. The thermal gas desorption rate and the photon stimulated gas desorption (PSD) rate were measured using the model duct. The fabrication was successful but large gas desorption rates were observed. We outline here the fabrication of the copper duct and report the experimental results.

II. FABRICATION OF A COPPER DUCT

A plan of the copper duct manufactured is presented in Figure 1. The duct consists of a beam channel, a pump channel and a cooling channel like a conventional beam duct. The duct is straight and the total length is 3.7 m. The aperture of the beam channel is 100 mm in width and 50 mm in height. The thickness of the duct wall is 6 mm. The pumping channel has three pumping ports for lumped ion pumps. The duct material is the Class 1 OFC (Oxide Free Copper) provided from HITACHI Cable, Ltd. The flanges are made of 304 stainless steel.

Each channel was independently extruded at first in a circular pipe with a proper size and then extracted to its design shape. They were welded each other by EBW (Electron Beam Welding). The length of the beam duct was limited by the volume (length) of EBW chamber at present. Due to the small total input power of EBW, the hardness of copper was not degraded except just near the welding point. The bend and the twist were also both less than 0.5 mm/m. The flanges were welded by TIG welding in Argon atmosphere inserting Inconel-625 between OFC and 304 stainless steel.

Since we had no definite idea to specify what surface treatment is the most appropriate for a copper beam duct, no special treatment was tried to the duct except for ultrasonic cleaning in a freon bath to get reference data for future studies. The roughness of the surface is less than 10 µm, but we can see many narrow lines on the surface along the duct marked in the extraction process.

After assembly, the duct received two cycles of baking up to 180°C and no air leak was detected. Constructing the vacuum system of copper beam duct has basically no technical problem.

III. MEASUREMENTS OF GAS DESORPTION RATES

A. Thermal gas desorption

The duct was evacuated by a turbo-molecular pump (300 l/s) and two ion pumps (130 l/s) combined with NEG pumps (100 l/s). Two B-A gauges measured the total pressures in the beam channel and the pump head. The pump down curve is shown in Figure 2. After a baking at 150°C for 48 hours, the pressure reached to about $1 \times 10^{-10}$ Torr at the beam channel in N$_2$ equivalent. The main residual gas was H$_2$. Ar was hardly detected. Assuming the total effective pumping speed of 300 l/s at the base pressure, the thermal gas desorption rate was calculated as about $1.5 \times 10^{-12}$ Torr l/(s. cm$^2$). This desorption rate is not so good value as a vacuum chamber. Carefully treated vacuum chambers of aluminum alloy or stainless steel give the thermal gas desorption rate in the order of or less than $10^{-13}$ Torr l/(s. cm$^2$).
3. Photon stimulated gas desorption (PSD)

The photon stimulated gas desorption rate was measured using the synchrotron radiation (SR) from the TRISTAN Accumulation Ring (AR) having a critical energy of 26.3 keV. Schematic diagram of the beam line is shown in Figure 3. The duct received the photon directly from the source at a 14.8 mrad incident angle. The x-y slit limited the photon beam vertical and horizontal opening angle to 0.50 mrad and 2.4 mrad, respectively. About 3 m out of 3.7 m long duct was directly irradiated by the SR with a height of about 8 mm. The incident photon flux $N_p$ per beam current per second was about $1.54 \times 10^{15}$ photons/$(mA \cdot s)$. The total pressures and partial pressures at the upstream and downstream side of the orifice ($O_r$) were measured by two extractor gauges (EXG1 and EXG2) and two quadrupole mass analyzer (QMA1 and QMA2), respectively. The photo-desorption coefficient $\eta_i$ for i-th gas species is given by

$$\eta_i = 3.3 \times 10^{19} \frac{C_i \Delta P_i}{N_p I_b} \text{ molecules/photon},$$

where $\Delta P_i$ is the pressure difference between the upstream and downstream side of the orifice in Torr, $C_i$ is the conductance of the orifice (50 mm width $\times$ 12 mm height) in l/s and $I_b$ is the beam current in mA. The downward beamline from the valve GV2 was baked up to 130°C for 48 hours. The base pressure of the copper duct was about $1 \times 10^{-9}$ Torr.

Main gases desorbed was $H_2$, $CH_4$, $CO$ and $CO_2$. The $\eta$ for these gas species as a function of photon dose are presented in Figure 4. The $\eta$ at the initial stage is in the order of $10^{-2}$ molecules/photon. The $\eta$ decreases with photon dose with an average slope of $-\frac{3}{5} \sim -1$ beyond $1 \times 10^{10}$ photons/m. The desorbed gas reached up to 1 Torr at $1 \times 10^{11}$ photons/m.

The $\eta$ and the total quantity of desorbed gases are larger by about one order of magnitude than the data of copper ducts reported so far by O.Gröbner et al.[2], A.G.Mathewson et al.[3], R.Gavaggio et al.[4] in DCI, and H.J.Halama et al. [5] in NSLS, and almost the same order as those of aluminum-alloy ducts [3,4,5]. All of copper duct refered, however, had received chemical etching be-
Figure 3. Schematic diagram of the beamline for PSD measurement.

Figure 4. Photo-desorption coefficients for H₂, CH₄, CO and CO₂ as a function of photon dose.

before the experiments. The large gas desorption from our model copper duct, therefore, will be due to the insufficient surface treatment.

IV. SUMMARY

A trial model of copper duct was fabricated with no mechanical problem. Constructing the vacuum system based on copper beam duct for the KEK B-Factory has no technical problem. The measured gas desorption rates were not good due to the insufficient surface treatment. Chemical surface cleaning will decrease the gas desorption rates. We are now planning to make several copper ducts with different surface treatments and to compare the η this year.

ACKNOWLEDGMENTS

The authors would like to thank Prof. S.Kurokawa for his continuous encouragement and the staffs of the TRISTAN Vacuum Group for their technical help in the experiments. They would thank Mr. M. Katane, Mr. T. Torii, Dr. S. Kakiuchi, Dr. T. Kobari (Hitachi Works, Hitachi, Ltd.) for their help in designing and fabricating a trial copper duct.

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